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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Liu

Application No.: 10/634,964

Filed: 8/5/2003

Title: CHEMICAL MECHANICAL
PLANARIZATION COMPOSITIONS FOR
REDUCING EROSION IN SEMICONDUCTOR

WAFERS

Attorney Docket No.: 02039US

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Art Unit:

Examiner:

Patricia A. George

4/5958 ENTER 8/27/07

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RESPONSE AFTER FINAL REJECTION

Dear Sir:

In response to the Office Action of February 5, 2007, having a shortened statutory deadline of May 5, 2007, please amend the specification as follows.